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Supplementary information

3 **Nano-injection System for Precise Direct Delivery of Biomolecules into** 4 **Single Cells**

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25 **Fabrication of microfluidic device**

26 The photomask film containing microchannel pattern of PDMS layer was designed using the
27 VCarvePro CAD software (Vectric Ltd., Redditch, UK). A SU-8 negative photoresist was coated by
28 a spin coater (ACE-200, Dong AH trade Corp., Seoul, Korea) on the base Si wafer and patterned to
29 make a mold using conventional photo-lithography (Fig. S1a). Then, a PDMS base and a curing agent
30 (SYLGARD® 184 Silicone Elastomer Kit, Dow corning Corp., Midland, MI, USA) were vigorously
31 mixed with a 10:1 ratio, and the glutinous mixture was subsequently poured onto the mold and cured
32 at 70 °C for 8 h in an incubator (Fig. S1b). The polymerized PDMS was peeled off from silicon masters
33 mold. Then, fluidic connections to an outside line were achieved by machining holes with a 1-mm
34 diameter biopsy punch (Kai medical Inc., Honolulu, HI, USA) (Fig. S1c). The PDMS was bonded on
35 top of the glass substrate by O₂ plasma bonding (CUTE, Femto science, Suwon, Korea) for 1 min (Fig.
36 S1d). It was named the “header chip”. Prior to nanoinjection structure fabrication, the microchannel
37 of header chip was washed three times with distilled water. Fig. S1e shows the schematic illustration
38 of the nanoinjection structure machined by using femtosecond-laser (fs-laser) in the bottom glass layer
39 of the header chip.

40

41 **fs-laser Machining system configuration**

42 The header chip was placed on a computer-controlled X-Y-Z axis (100 μm × 100 μm × 100 μm) piezo-
43 stage (Nano-LP100, Mad city labs Inc., Madison, WI, USA) for 3-D nano-machining. The
44 nanoinjection structure inside the glass layer (Fig. S2) was formed using the fs-laser machining system
45 (Femtobiomed, Seongnam, Korea) described in detail elsewhere^{1,2}. The laser pulse, whose wavelength
46 was 513 nm (50 mW) wavelength with a frequency of 2 kHz, was used for glass processing (Fig. S3).

47

48 **SEM imaging**

49 To evaluate the influence of the fs-laser melting parameters in the glass layer, different parameters
50 were evaluated: Spindle speed (laser intensity, μm), feed rate (laser speed, μm/min), start depth (laser
51 melting point, μm). The morphology of the fs-laser induced glass surface modifications was analyzed

52 by a Scanning Electron Microscope (SEM) (Fig. S4). For this purpose, the sample was coated with a
53 Pt layer using a Cressington 208 HR sputter coater under an argon atmosphere. The coated samples
54 were examined and imaged by a JEOL JSM-7401F at an accelerating voltage of 5.0 kV. SEM images
55 analysis revealed the optimal combination of parameters at value of spindle speed, feed rate, start
56 depth which are 8000 rpm, 480 $\mu\text{m}/\text{min}$, 0 μm -Z axis, respectively, and the nanoinjection structure
57 was fabricated under optimal parameters.

58

59 **Channel Resistance of nanoinjection system**

60 The electrolyte conductivity (σ) and resistivity (ρ) are the parameters connected with the purity of the
61 water. The electrical conductivities of the electrolytes were measured using a conductivity meter
62 (TI9000, Trans instruments Ltd., Singapore). Electrolyte conductivity is expressed as microsimens per
63 centimeter ($\mu\text{S}/\text{cm}$). Resistance (ρ) is the reciprocal of conductivity and is expressed as the ohm-meter
64 (Ωm). When voltage is applied to the aqueous solution, the electric current is generated by the flow of
65 the ions in the solution; therefore, the electric current flows abundantly if many ions are present, while
66 the conductivity is high if the resistance is low. Moreover, conductivity and resistance are influenced
67 by the temperature. This research proceeded in a laboratory that was maintained at room temperature.

68 The conductivity of the solution was measured according to the electric current passing through the
69 electrode that was connected to the solution-filled microtube. The D-PBS conductivity, represented as
70 D-PBS $_{\sigma}$, was then calculated using the following equation (1):

71

$$\sigma [S/m] = \frac{L [m]}{R [\Omega] \times A [m^2]} \quad (1)$$

72

73

74 where R is the microtube resistance, L is the length of the channel, and A is the cross-sectional area
75 of the microtube.

76 To measure the channel resistance, the D-PBS solution was filled in the header chip channel where
77 the nano-injection structure is included. The flow resistance of all the channels in the header chip is
78 approximated by the following equation (2):

$$R [\Omega] = \frac{\rho [\Omega m^2 / m] \times L [m]}{A [m^2]} \quad (2)$$

80
81 Also, we can obtain an expression for $L[m]/A[m^2]$ in the geometries of the PDMS microchannel using
82 the measured values of the oscilloscope resistance, applied voltage, and D-PBS conductivity.

83 The microchannel resistance of a nano-injection structure is easily calculable using the equation (2).
84 The nanochannel size of the nano-injection structure was influenced by the laser intensity because of
85 the fs-laser focal-spot size. therefore, the pore diameter of the nanochannels is adjustable with the use
86 of the laser intensity. Here, we fabricated nanochannel with diameters of 800 nm. The resistivity of
87 all the channels is marked on Table S1.

88

89 **Cell viability**

90 We confirmed the viability of cells before and after processing the cells on the nano-injection system
91 (CellShot™ platform, supplier: Femtobiomed Inc.). After electrical stimulation, the collected cells
92 were stained using Calcein-AM (Sigma-Aldrich, St. Louis, MO, USA) used to label living cells. 2 μM
93 calcein-AM were incubated with the sample for 30 min at room temperature. The phase difference
94 and fluorescence images of the cells were obtained for image processing.

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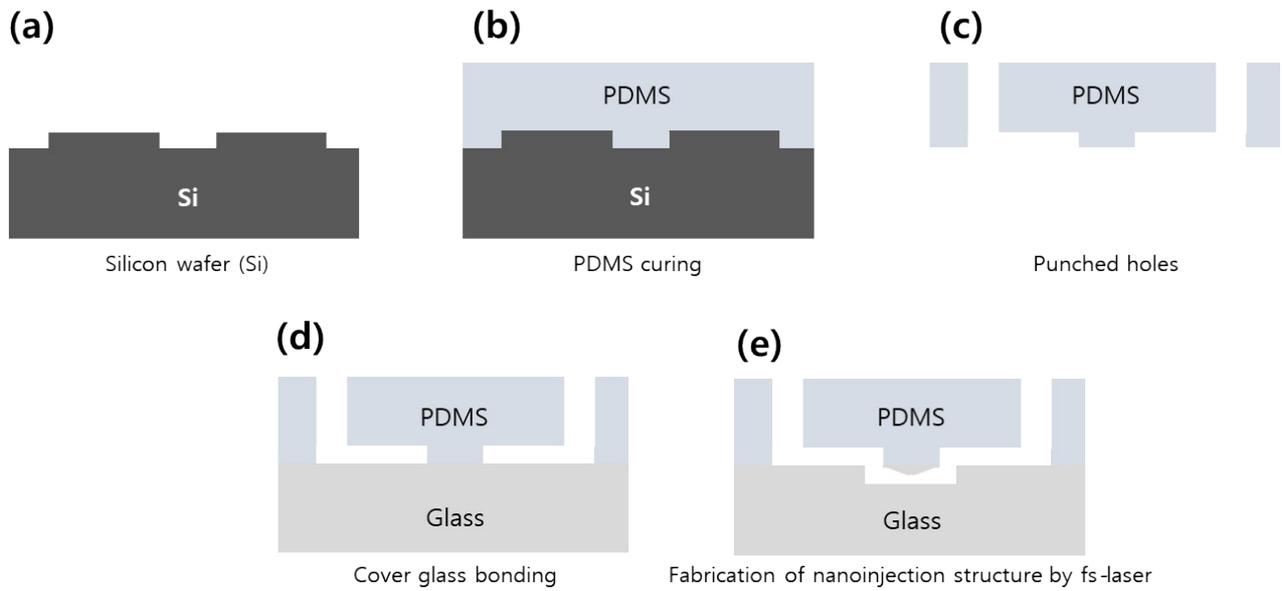
100

101 **Reference**

102 1 S. Lee, *Univ. Mich.*, 2008, **Doctor of Philosophy**, 128.

103 2 S. Lee, R. An and A. J. Hunt, *Nat. Nanotechnol.*, 2010, **5**, 412–416.

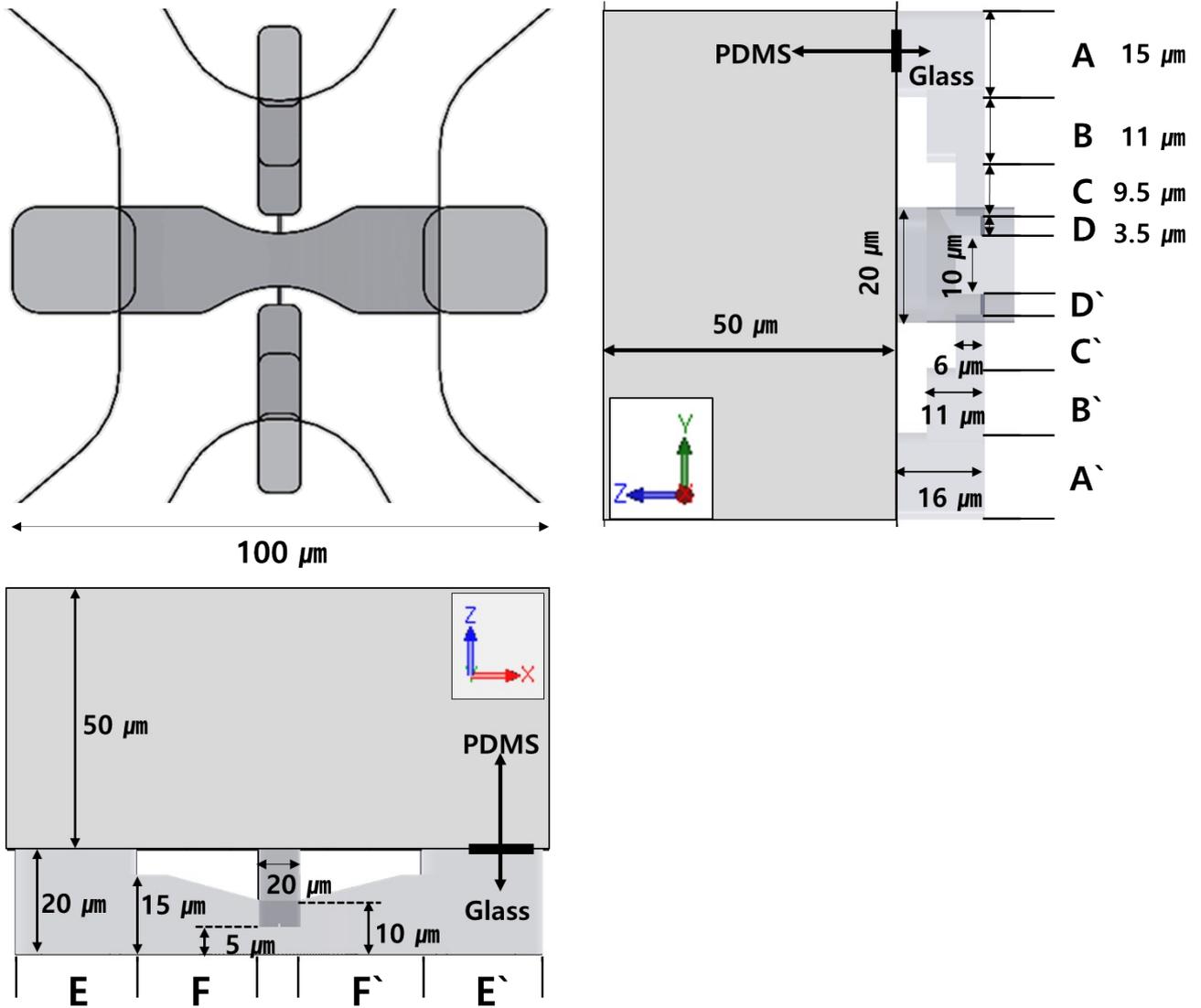
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106 **Fig. S1** Fabrication process of header chip and nanostructure. The soft lithography
 107 techniques are combined with the laminated object manufacturing techniques. (a-c) Transferring the
 108 pattern from a Si wafer onto the PDMS mold. (d) Pre-mold with microchannel structure of a header
 109 chip was bonded to the cover glass. (e) Nanostructure machined by using the fs-laser in the
 110 bottom glass layer.

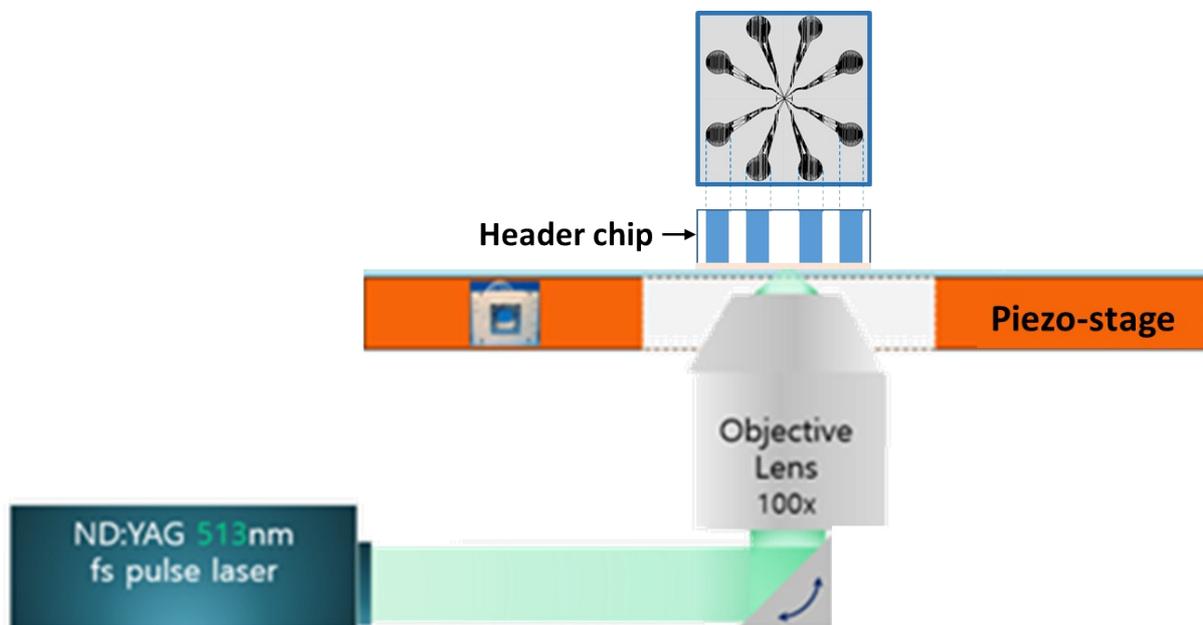
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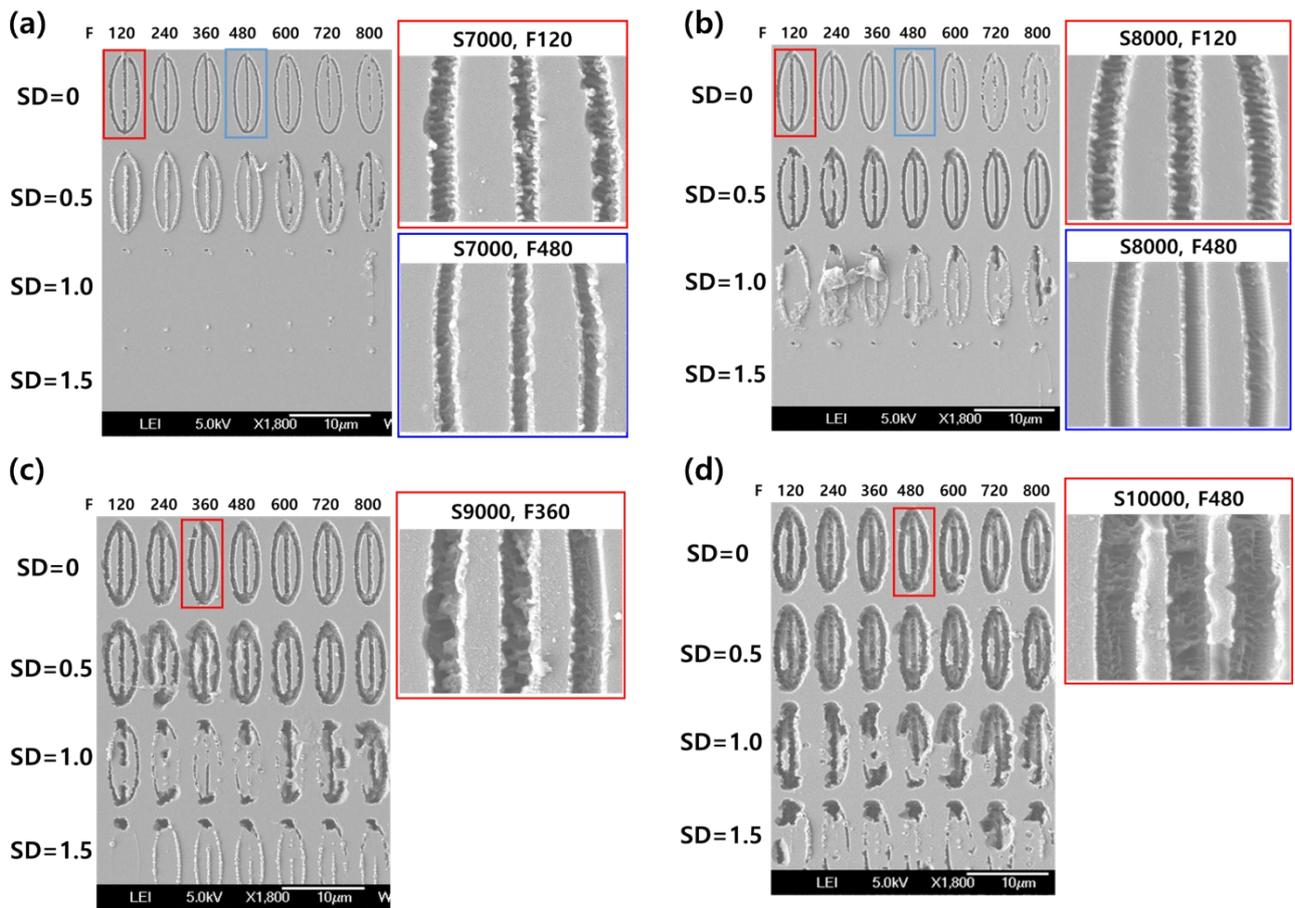
114 **Fig. S2** Standard specification of nanoinjection structure. A-C, A'-C': charge (+, -) channel; D, D':

115 Nanochannel; E-F, E'-F': Cell-loading channel.



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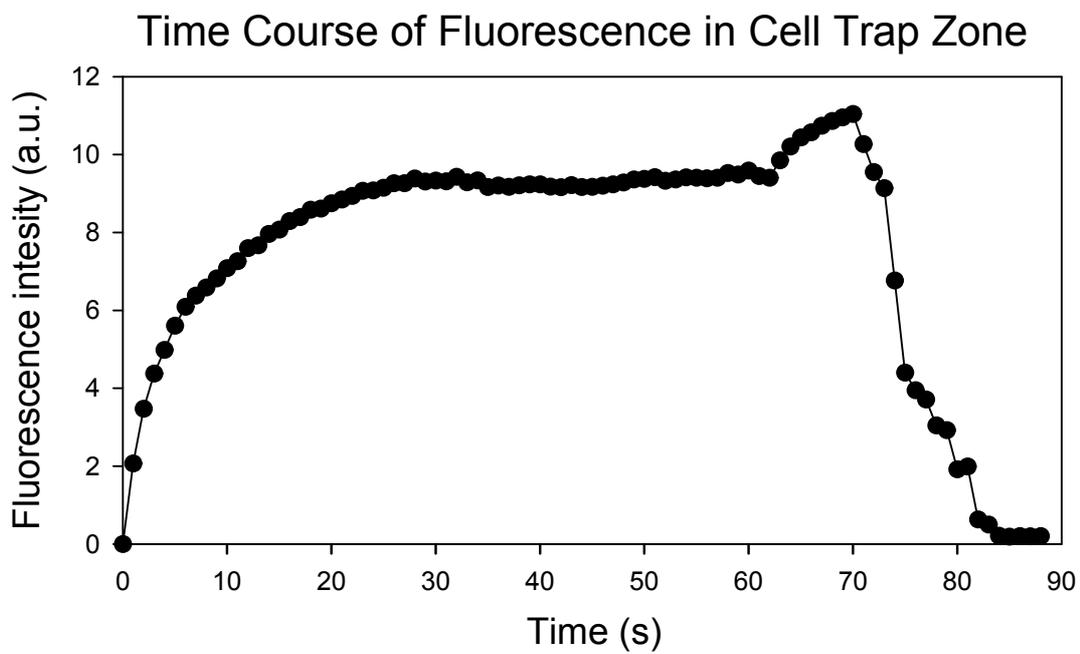
117 **Fig. S3** Schematic diagram of a fs-laser machining system for fabrication of nanostructure.



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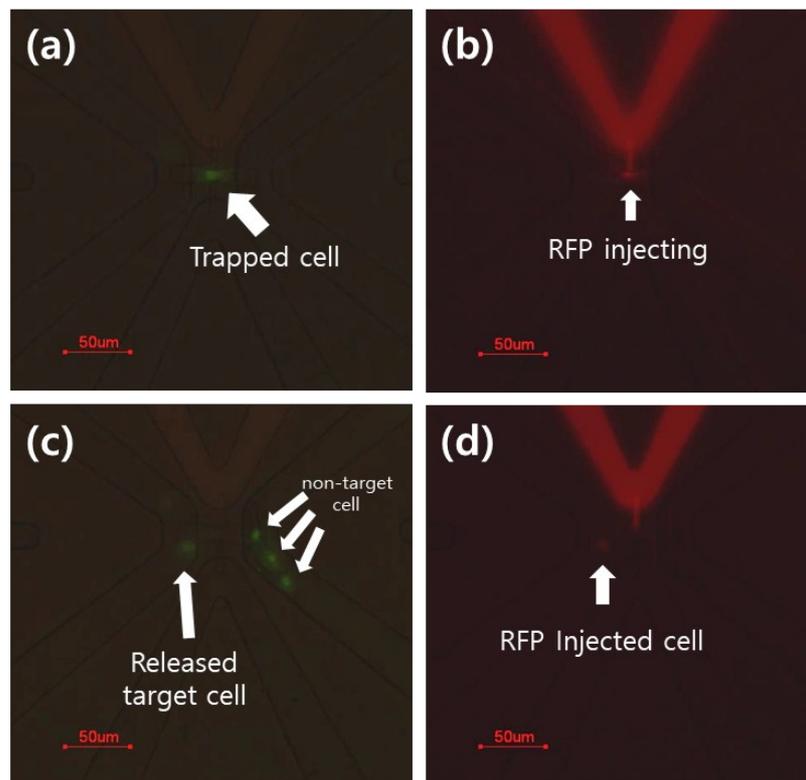
121 **Fig. S4** SEM images of line-ellipse patterns formed using fs-laser. (a-d) are SEM images prepared at
 122 Spindle speed (S, laser intensity) of 7000, 8000, 9000, and 10000 rpm, respectively. The tests were
 123 carried out at feed rate (F, laser speed) up to 800 $\mu\text{m}/\text{min}$ and start depth (SD, laser melting point) up
 124 to 1.5 μm -Z axis.



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127 **Fig. S5** RFP fluorescence intensity inside the cells separated by pulse duration.

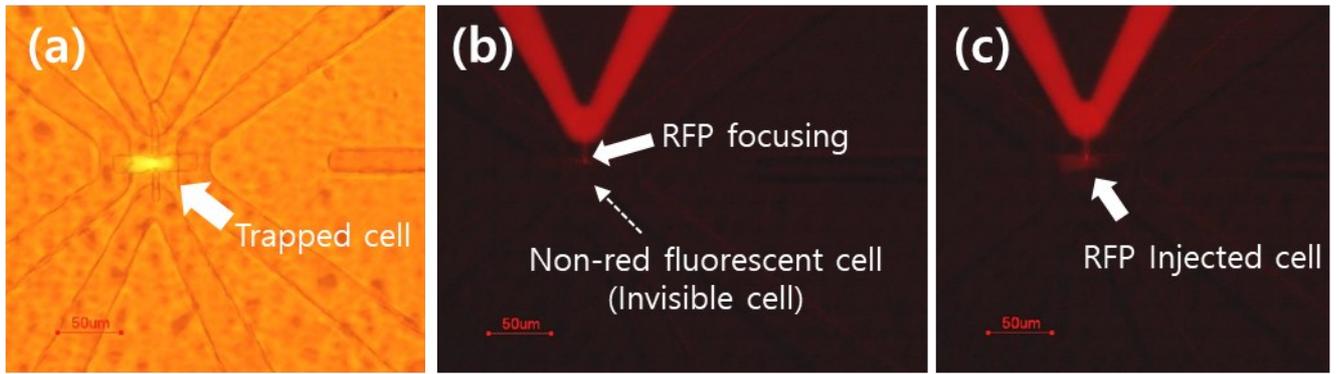


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131 **Fig. S6** Fluorescence image of RFP-injected into a human umbilical cord-derived stem cells (hUC-
 132 MSC). (a) Trapped cell (Green: CalceinAM), (b) RFP-injected cell, (c) Comparison of target cell and
 133 non-target cells with fluorescence (Green: CalceinAM), (d) Comparison of target cell and non-target
 134 cells with fluorescence (Red: RFP).

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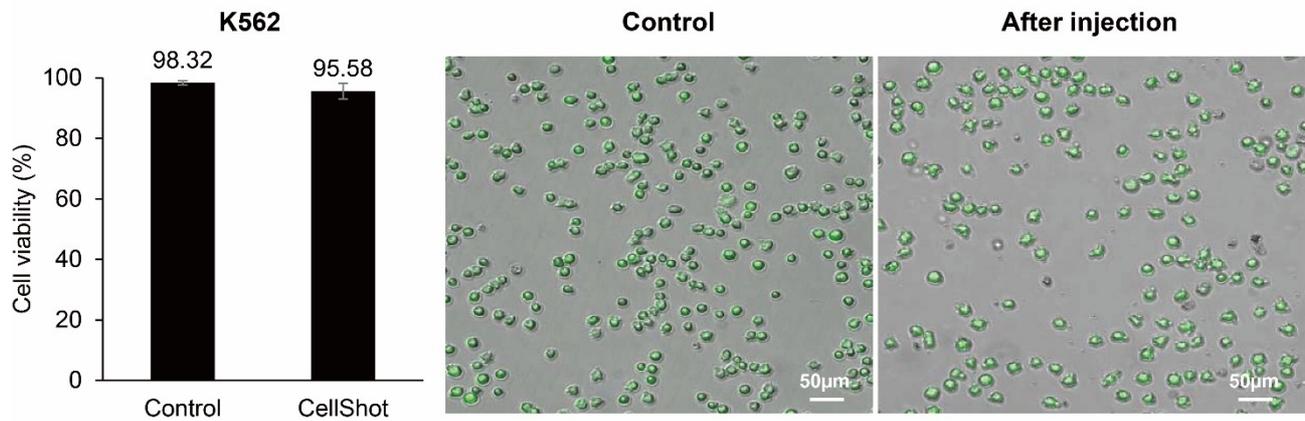


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137 **Fig. S7** Fluorescence image of RFP-injected into a A549 cell. (a) Trapped cell (Green: CalceinAM),

138 (b) Non-red fluorescent trapped cell, (c) RFP-injected cell (Red: RFP).

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140

141 **Fig. S8** Quantitative image analysis of cell viability based on immunofluorescence intensity. The cell
 142 viability after treated in nanoinjection system is >95% for K562 cells (human immortalized
 143 myelogenous leukemia cell line). The cell viability was confirmed by Calcein-AM staining. The data
 144 were expressed as mean \pm standard error (# of live cells / #of collected cells).

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Supplementary table

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Channel		Resistance (ohm, Ω)	Sub. Total (ohm, Ω)	Voltage (V)	
Positive (+) charge channel inlet	PDMS channel	645,484	645,484	0.13	
	Top microchannel	A	85,470	306,268	0.06
		B	85,470		
		C	135,328		
Top nanochannel	D	4,642,019	4,642,019	1.0	
Negative (-) charge channel inlet	Bottom nanochannel	D'	4,642,019	4,642,019	1.0
	Bottom microchannel	C'	135,328	158,333	0.06
		B'	85,470		
		A'	85,470		
PDMS channel		645,484	710,960	0.13	
Oscilloscope		1,000,000	1,000,000	0.21	
Total			7,349,154	2.5	

149

150 **Table S1** Nano and microchannel resistance of nanoinjection structure. The distribution of the applied
 151 voltage of 2.5 V of an integrated electrode on a nanoinjection system.

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153

Supplementary movie

155 **Movie S1** RFP fluorophore flow without cell.

156 **Movie S2** RFP fluorescence intensity inside the cells by pulse duration.

157 **Movie S3** Destruction of living cell in nanoinjection system by high-voltage application.

158 **Movie S4** Continuous intracellular delivery process.